

FIG. 1

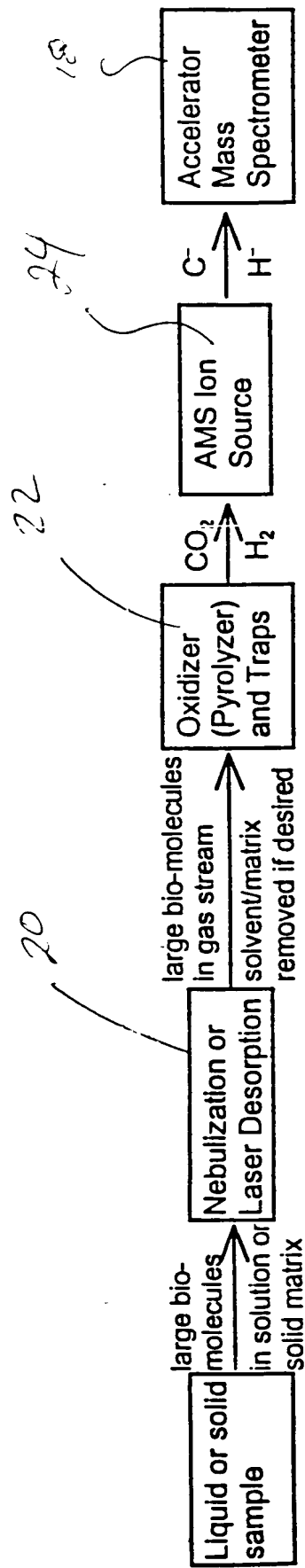


FIG. 2

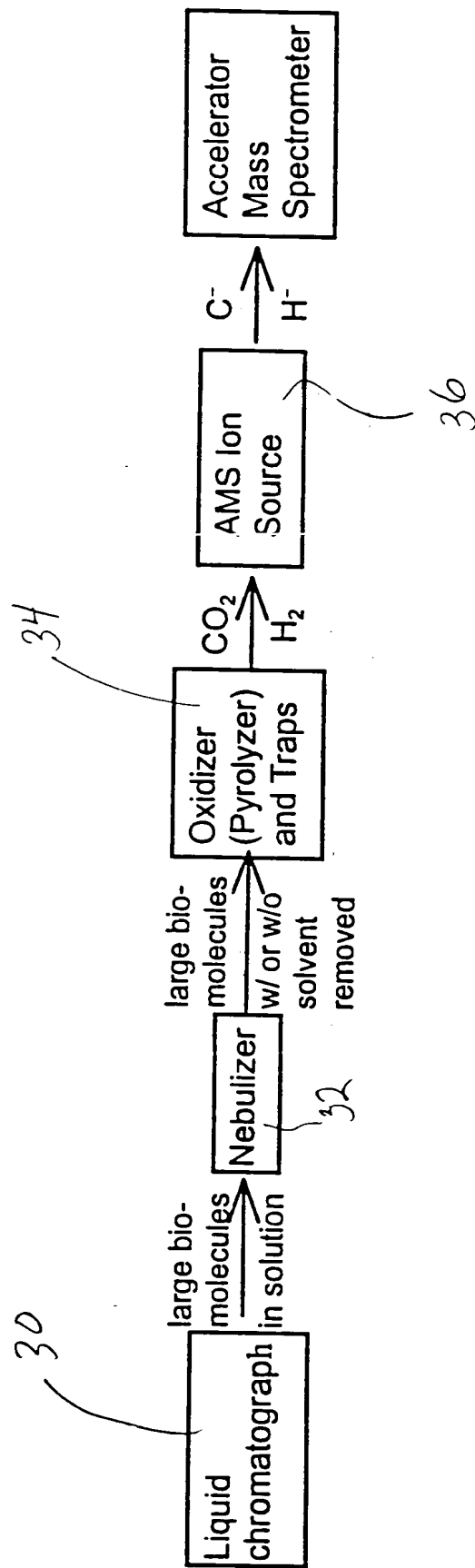


FIG. 3

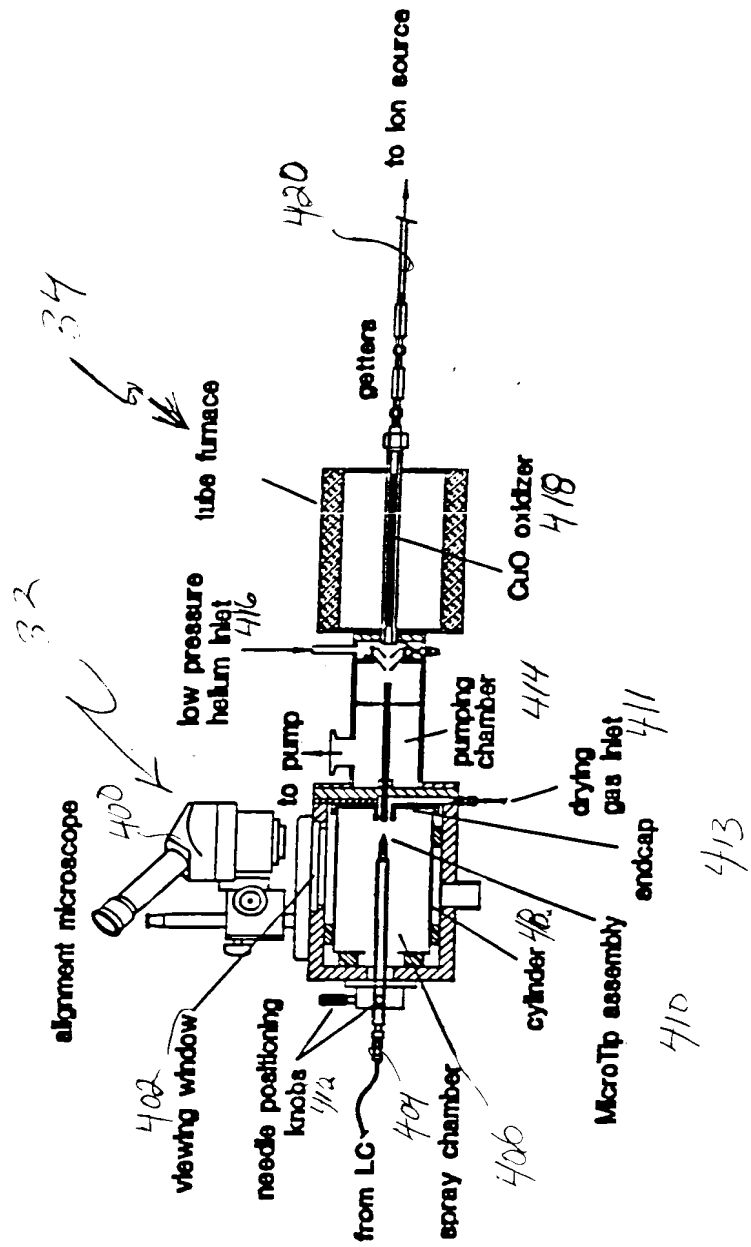


FIG. 4A

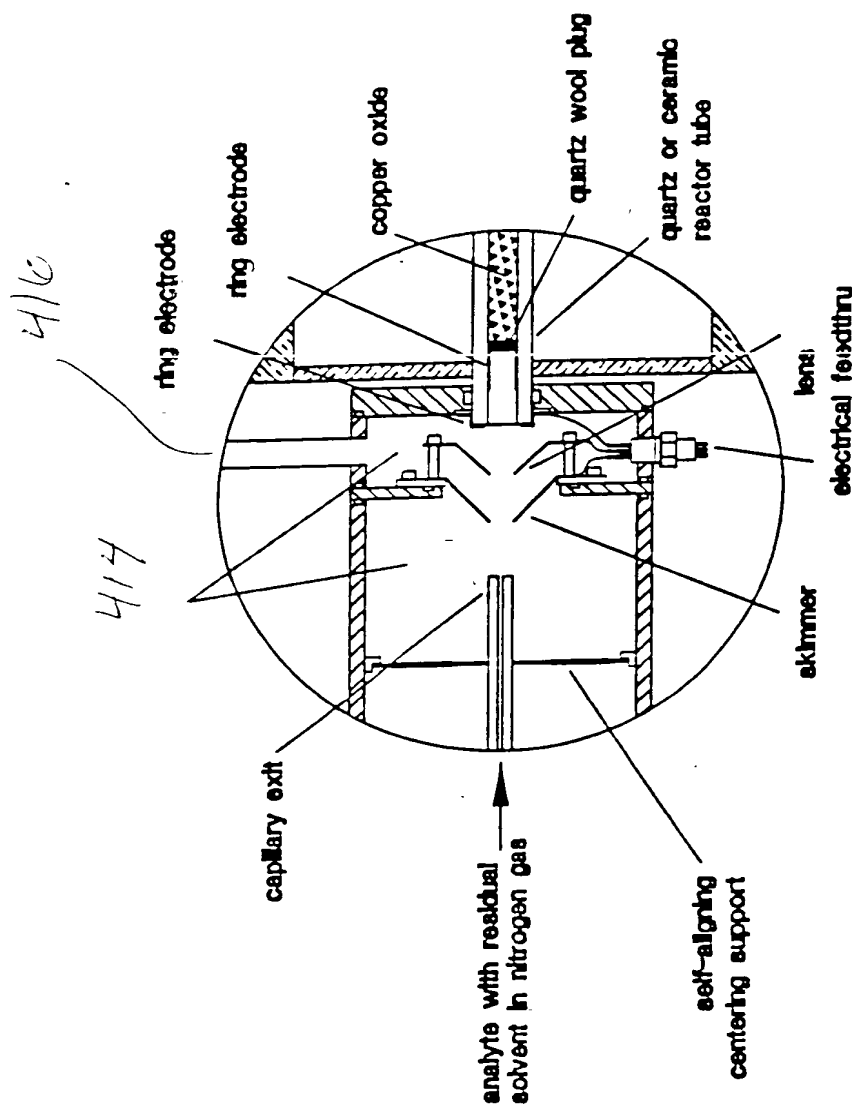


FIG. 4B

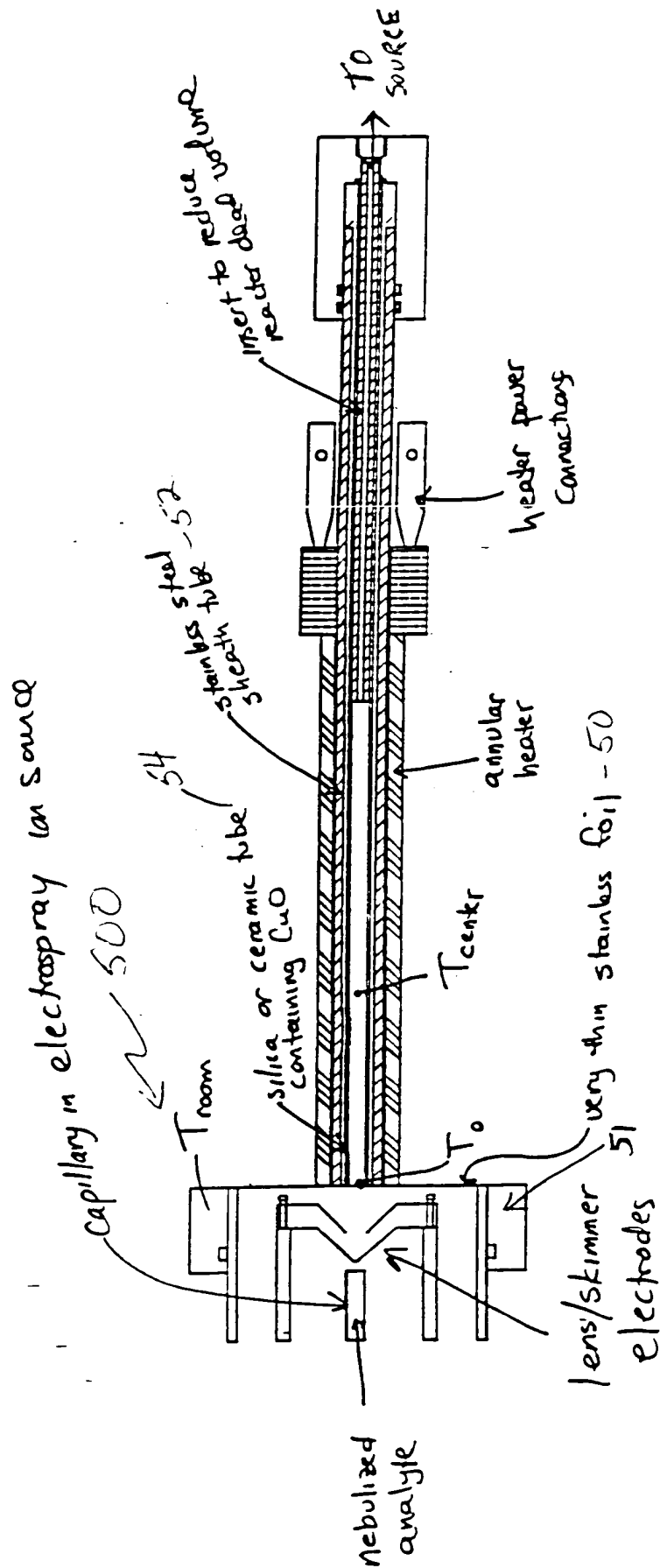


FIG. 5

FIG. 6B

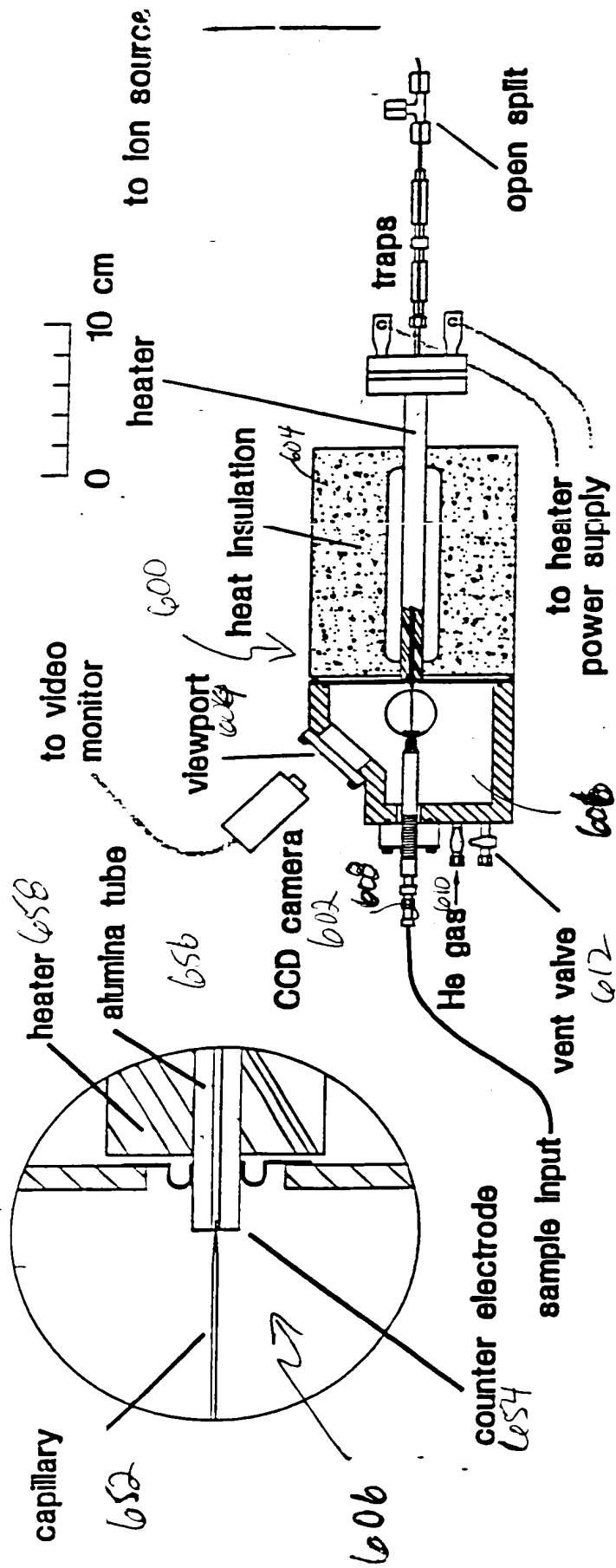


FIG. 6A

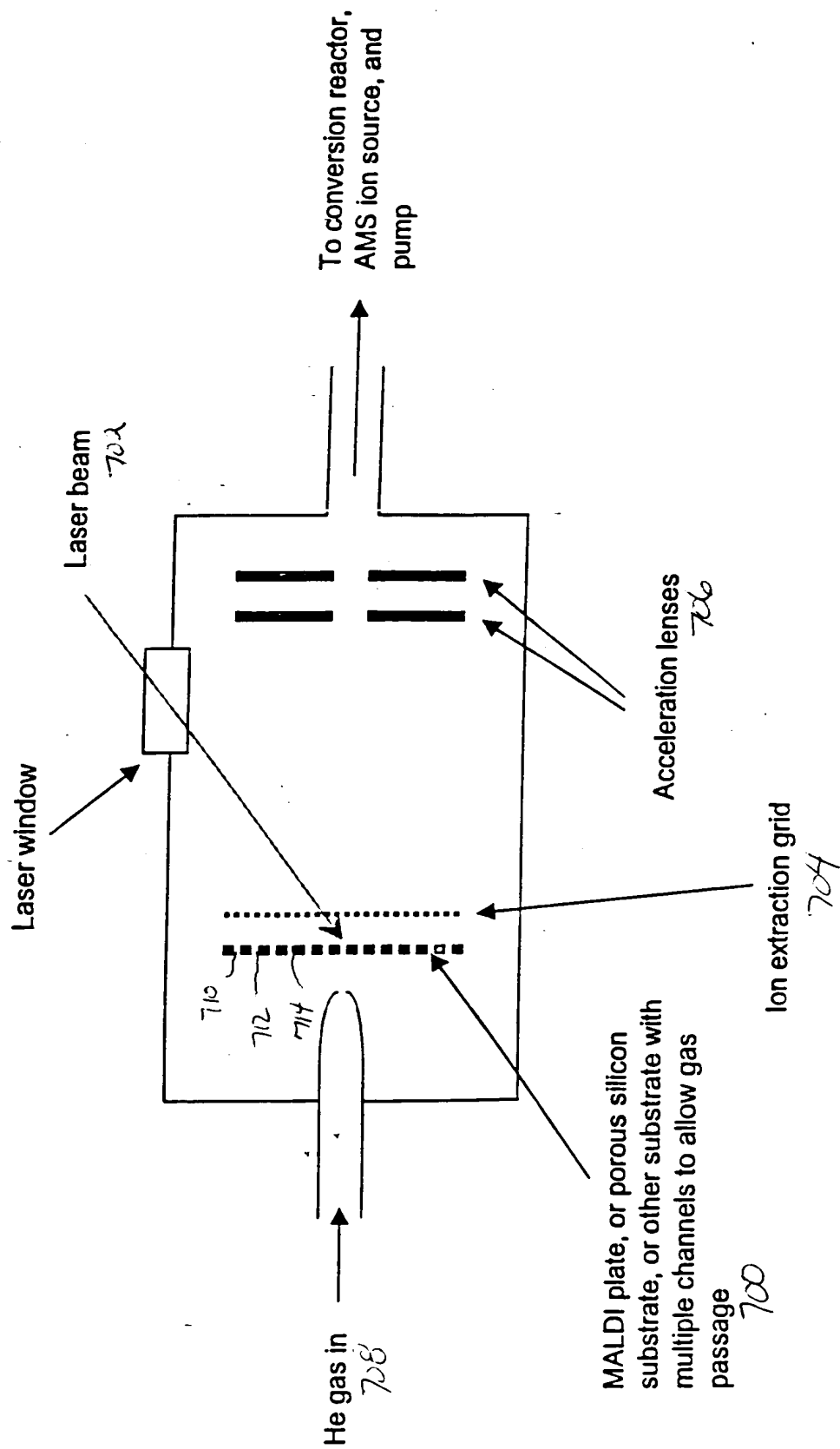


FIG. 7

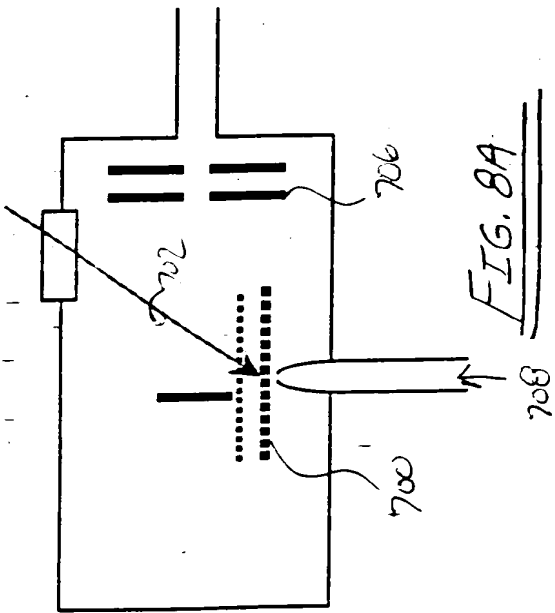


FIG. 8A

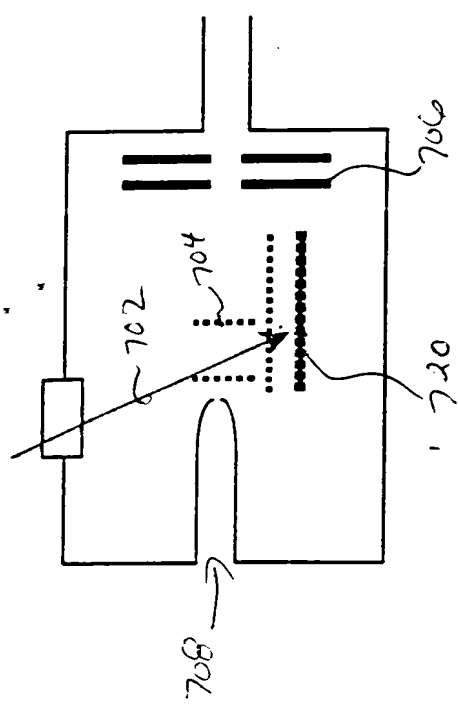


FIG. 8C

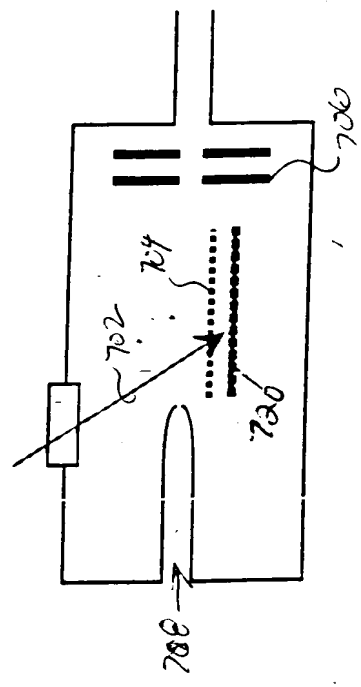


FIG. 8B

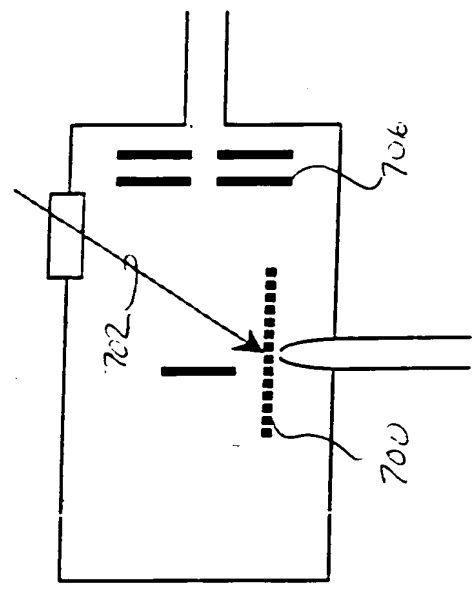


FIG. 8D

Sample dispensing
apparatus

Sample input

Sample bed

substrate

Sample applied
to sample bed

Sample deposition

FIG. 9A

Laser beam

Converted
chemical form

Sweep gas in

Laser-induced conversion

FIG. 9B

Pipetter

Sample input
(e.g. HPLC eluent)

Thin layer of
CuO catalyst
10-2

Refractory substrate

Sample applied
to CuO bed

Sample deposition

FIG. 10A

Laser beam

CO₂ in He
to AMS ion source
or other apparatus

He gas in

Laser-induced combustion

FIG. 10B

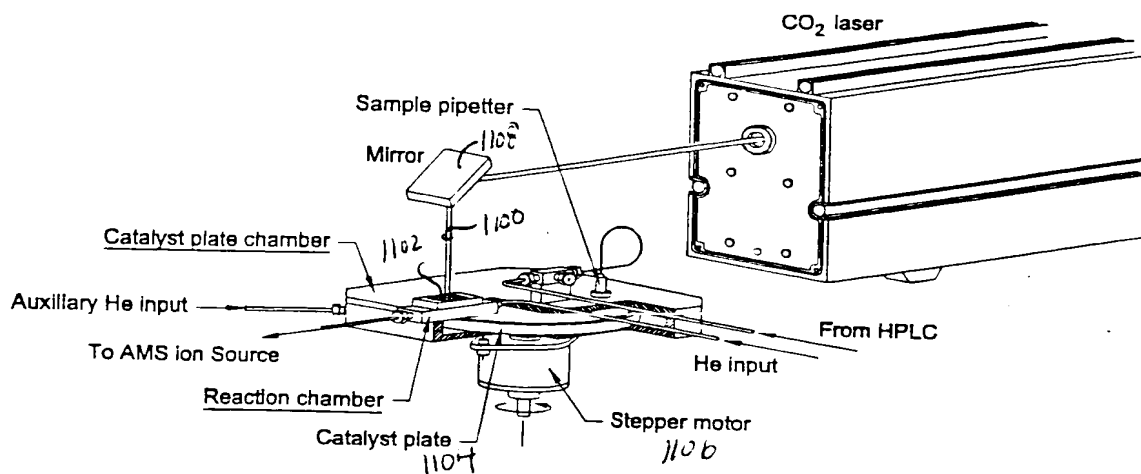


FIG. 11A

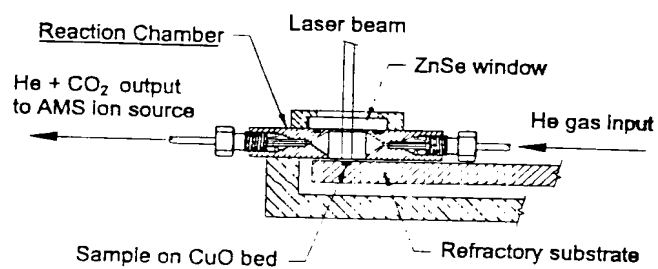


FIG. 11B

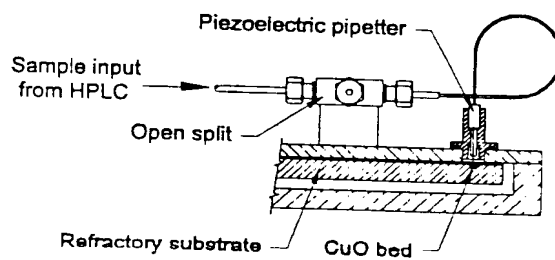


FIG. 11C

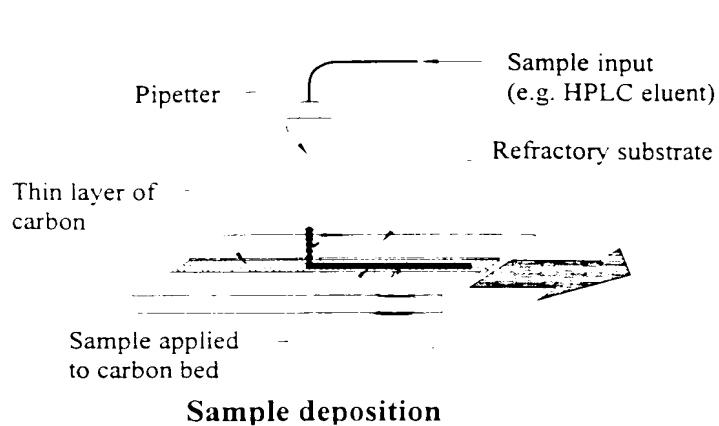


FIG. 12A

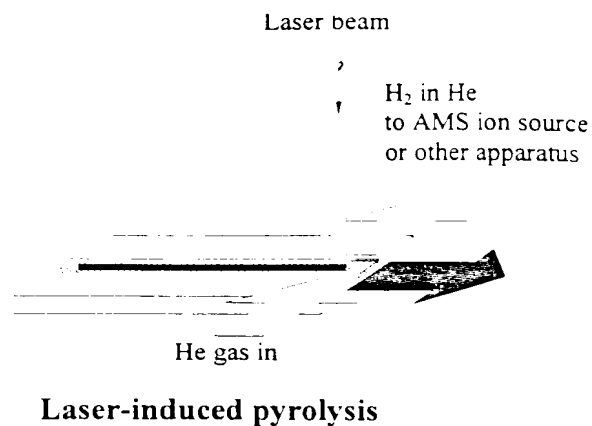


FIG. 12B

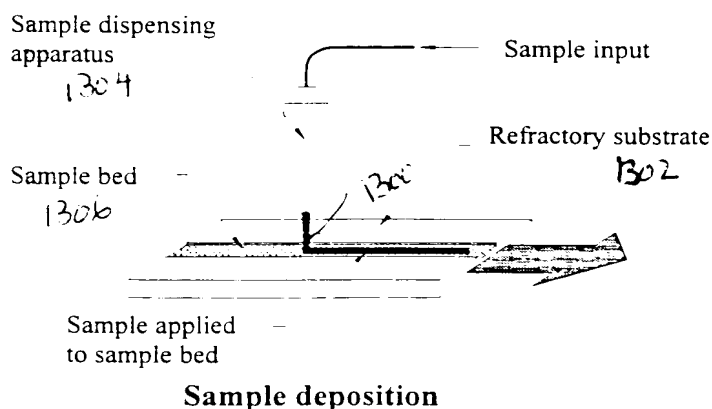


FIG. 13A

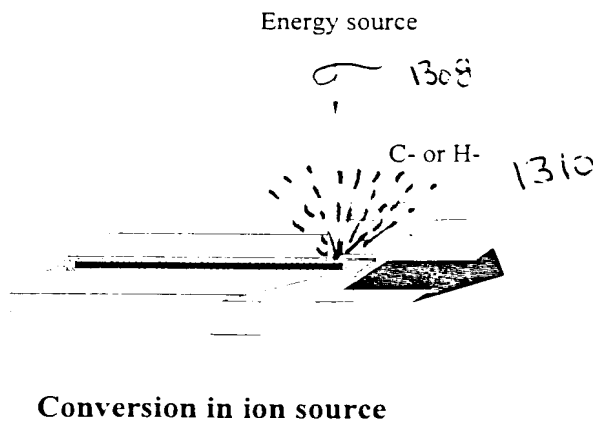
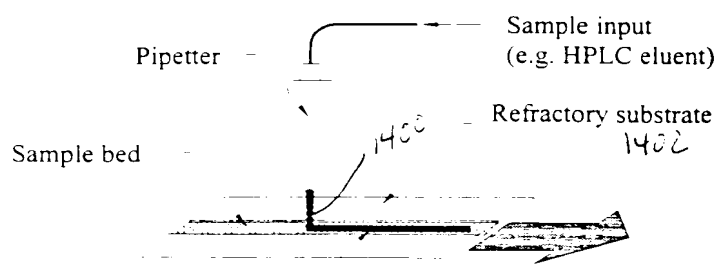
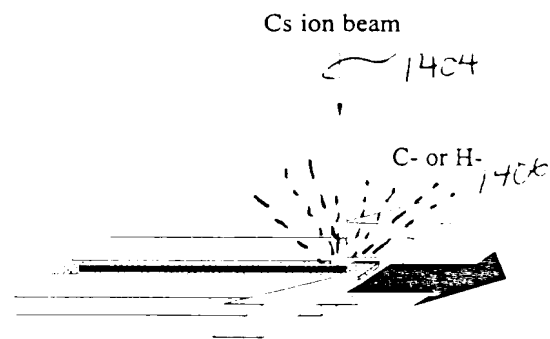


FIG. 13B



Sample deposition

FIG. 14A



Conversion in ion source

FIG. 14B

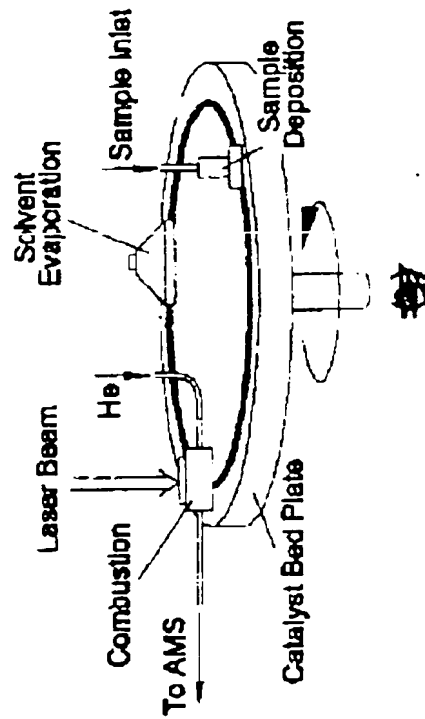


FIG. 15

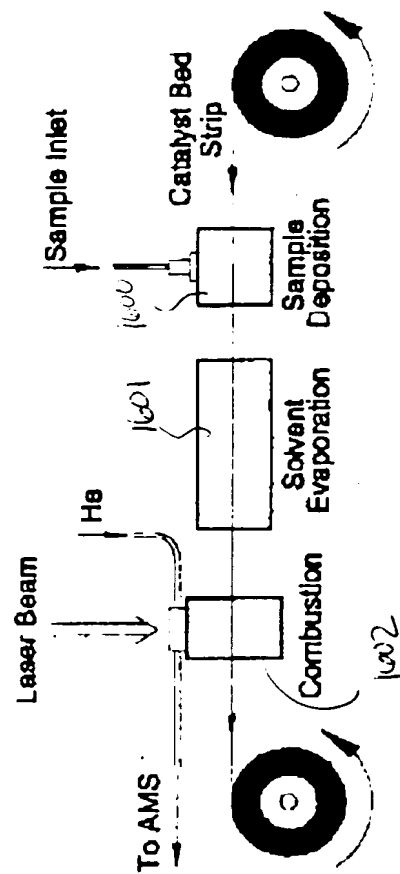


FIG. 16